IN THE CLAIMS

Please amend claims 8, 9, 14, 15, 18-21, 68, 71-74, and 132 as follows.

1. (previously presented) A spatial light modulator comprising:

an array of micromirrors, each micromirror comprising a mirror plate having four predominant sides and being held on a substrate by a plurality of posts, wherein the four predominant sides define two diagonals, and wherein a line between any two of the plurality of posts is not coincident with either of the two diagonals; wherein the mirror plate is attached to a hinge that is supported by a post of the plurality of posts on the substrate; and wherein the mirror plate and hinge are separated by a gap in a direction perpendicular to the mirror plate when the mirror plate is parallel to the substrate.

- 2. (previously presented) The spatial light modulator of claim 1, wherein each mirror plate is in a shape of a rectangle, square, trapezoid or rhombus.
- 3. (previously presented) The spatial light modulator of claim 2, wherein the mirror plate is in a shape of square.
- 4. (original) The spatial light modulator of claim 1, wherein the plurality of posts consists of two posts.
- 5. (previously presented) The spatial light modulator of claim 1, wherein the substrate has four predominant sides that form a rectangular shape; and wherein each side of the mirror plate is at an angle of from 5° degrees to 25° degrees to the two sides of the rectangular substrate.
- 6. (previously presented) The spatial light modulator of claim 1, wherein the substrate has four predominant sides that form a rectangular shape; and wherein each side of the mirror plate is at an angle of from 10° degrees to 20° degrees to the two sides of the rectangular substrate.
- 7. (previously presented) The spatial light modulator of claim 1, wherein the mirror plate is attached to the hinge such that the mirror plate is capable of rotating along a rotation axis that is parallel to but offset from a diagonal of the mirror plate when viewed from the top of the substrate.
- 8. (currently amended) The spatial light modulator of claim 7, wherein the micromitror further

comprises:

a first an electrode placed proximate to the mirror plate such that a first electrical field filed is established between the first electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a first rotation direction in response to the first electrical field.

9. (currently amended) The spatial light modulator of claim 8 7, wherein said electrode is a first electrode, and wherein the micromitror further comprises:

a second electrode placed proximate to the mirror plate such that a second electrical field filed is established between the second electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a second rotation direction in response to the first electrical field, wherein the second rotation direction is opposite to the first rotation direction.

- 10. (original) The spatial light modulator of claim 9, wherein the first and the second electrode are on a substrate other than the substrate to which the hinge support is connected.
- 11. (original) The spatial light modulator of claim 9, wherein the first electrode is on a substrate other than the substrate to which the hinge support is connected; and wherein the second electrode is on the substrate to which the hinge support is connected.
- 12. (original) The spatial light modulator of claim 11, wherein the second electrode is an electrode film on a surface of the substrate to which the hinge support is connected.
- 13. (original) The spatial light modulator of claim 7, wherein the micromirror further comprises: an extension plate connected to the mirror plate.
- 14. (currently amended) The spatial light modulator of claim 13, wherein the extension plate is connected to the mirror plate via an extension-plate post and the extension plate defines a first gap between the extension plate and the mirror plate.
- 15. (currently amended) The spatial light modulator of claim 14 13, wherein said gap between the extension plate and the mirror plate is a first gap; and wherein the extension plate is extended beyond the mirror plate and connected to the mirror plate via an extension-plate post; and wherein the extension plate defines a second gap between the extension plate and the substrate to which the hinge support is

connected.

- 16. (original) The spatial light modulator of claim 13, wherein the extension plate is electrically conducting.
- 17. (original) The spatial light modulator of claim 13, wherein the extension plate is dielectric with a dielectric constant larger than 1.0.
- 18. (currently amended) The spatial light modulator of claim 7, wherein the micromirror further comprises:
- a first stop for stopping the rotation of the mirror plate when the mirror plate rotates to an ON state angle.
- 19. (currently amended) The spatial light modulator of claim 18, wherein the first stop is disposed on the hinge support.
- 20. (currently amended) The spatial light modulator of claim 7, wherein the micromirror further comprises:
- a second stop for stopping the rotation of the mirror plate when the mirror plate rotates to an OFF state.
- 21. (currently amended) The spatial light modulator of claim 20, wherein the second stop is disposed on the hinge support.
- 22. (original) The spatial light modulator of claim 1, wherein the substrate has an anti-reflection film on a surface of the substrate.
- 23-62. (cancelled)
- 63. (previously presented) A spatial light modulator comprising:
- an array of micromirrors, each micromirror comprising a mirror plate held on a substrate by a plurality of posts, each mirror plate having four predominant sides; wherein the substrate is in a rectangular shape; and wherein each side of the mirror plate is at an angle of from 5° to 25° degrees to the

two predominant sides of the rectangular substrate.

- 64. (previously presented) The spatial light modulator of claim 63, wherein the mirror plates are rectangular or square.
- 65. cancelled
- 66. (previously presented) The spatial light modulator of claim 63, wherein the substrate is in a rectangular shape; and wherein each side of the mirror plates is at an angle of from 10° degrees to 20° degrees to the two sides of the rectangular substrate.
- 67. (previously presented) The spatial light modulator of claim 63, wherein each micromirror further comprises:
 - a hinge support held by the posts on the substrate and connected to the substrate via the posts;
 - a hinge affixed to the hinge support; and
- wherein the mirror plate is attached to the hinge such that the mirror plate is capable of rotating along a rotation axis that is parallel to but offset from a diagonal of the mirror plate when viewed from the top of the substrate.
- 68. (currently amended) The spatial light modulator of claim 67, wherein the micromirror further comprises:
- a first electrode placed proximate to the mirror plate such that a first electrical field filed is established between the first electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a first rotation direction in response to the first electrical field; and
- a second electrode placed proximate to the mirror plate such that a second electrical field filed is established between the second electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a second rotation direction in response to the first electrical field, wherein the second rotation direction is opposite to the first rotation direction.
- 69. (original) The spatial light modulator of claim 68, wherein the second electrode is an electrode film on a surface of the substrate to which the hinge support is connected.
- 70. (original) The spatial light modulator of claim 67, wherein the micromirror further comprises:

an extension plate connected to the mirror plate.

- 71. (currently amended) The spatial light modulator of claim 70, wherein the extension plate is connected to the mirror plate via an extension-plate post and the extension plate defines a first gap between the extension and the mirror plate.
- 72. (currently amended) The spatial light modulator of claim 70, wherein the extension plate is extended beyond the mirror plate and connected to the mirror plate via an extension-plate post; and wherein the extension plate defines a second gap between the extension plate and the substrate to which the hinge support is connected.
- 73. (currently amended) The spatial light modulator of claim 63, wherein the micromirror further comprises:
- a first stop for stopping the rotation of the mirror plate when the mirror plate rotates to an ON state angle.
- 74. (currently amended) The spatial light modulator of claim 63, wherein the micromirror further comprises:
- a second stop for stopping the rotation of the mirror plate when the mirror plate rotates to an OFF state.

75-126. (cancelled)

127. (previously presented) A spatial light modulator comprising:

an array of micromirrors, each micromirror comprising a mirror plate that comprises four predominant sides and being held on the substrate by a plurality of posts, wherein the four predominant sides define two diagonals, and wherein a line connecting the centers of any two of the plurality of posts is not coincident with either of the two diagonals of the mirror plate; and

wherein the mirror plate is attached to a hinge that is supported by at least one of the plurality of posts; and wherein the mirror plate and hinge are separated by a gap in a direction perpendicular to the substrate when the mirror plate is parallel to the substrate.

- 128. (previously presented) The spatial light modulator of claim 127, wherein the substrate is in a rectangular shape; and wherein each side of the mirror plate is at an angle of from 5° to 25° degrees to the two predominant sides of the rectangular substrate.
- 129. (cancelled)
- 130. (previously presented) The spatial light modulator of claim 127, wherein the substrate is in a rectangular shape; and wherein each side of the mirror plate is at an angle of from 10° degrees to 20° degrees to the two sides of the rectangular substrate.
- 131. (previously presented) The spatial light modulator of claim 127, wherein the mirror plate is attached to the hinge such that the mirror plate is capable of rotating along a rotation axis that is parallel to but offset from a diagonal of the mirror plate when viewed from the top of the substrate.
- 132. (currently amended) The spatial light modulator of claim 127, wherein the micromirror further comprises:
- a first electrode placed proximate to the mirror plate such that a first electrical <u>field</u> filed is established between the first electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a first rotation direction in response to the first electrical field; and
- a second electrode placed proximate to the mirror plate such that a second electrical <u>field</u> filed is established between the second electrode and the mirror plate, and the mirror plate rotates relative to the substrate in a second rotation direction in response to the first electrical field, wherein the second rotation direction is opposite to the first rotation direction.
- 133. (previously presented) The spatial light modulator of claim 127, wherein the micromitror further comprises:
 - an extension plate connected to the mirror plate.